INFORMATION DISCLOSURE STATEMENT BY APPLICANTS PTO FORM 1449

Atty. Docket No. 10191/1924	Serial No. To Be Assigned	V-
Applicant(s) BENZEL et al.		270
Filing Date Herewith	Group To Be Assigned	S. U.S.

U. S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE
γ	5,714,791*	Feb. 3, 1998	CHI et al.			
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^{*} Described in the Specification.

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
		22		02.100	565 62.155	YES	NO
i.	WO 96 05506* *	Feb. 22, 1996	PCT				

^{*} Described in the Specification.

OTHER DOCUMENTS

EXAMINER'S INITIALS	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
<u>I</u>	D. Heinze, Semiconductor Technologies for Manufacturing Modern Moisture Sensors, Sensor 91, Nuremberg 1991, Kongreßband (Convention Volume) IV, 112-121).*
M	Lammel et al., Free-standing Mobile 3D Microstructures of Porous Silicon, Proceedings of the 13th European Conference on Solid-State Transducers, Eurosensors XIII, The Hague, 1999, 535-536.*

^{*} Described in the Specification.

EXAMINER DATE CONSIDERED 11-7-07

EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.